

Standardized MEMS Manufacturing Process

Micragem™ Process



Step One:

Begin with a glass wafer. Etch cavities in glass and pattern electrodes, lines and bond pads.



Step Two:

Anodically bond SOI wafer to glass.



Step Three:

Etch back silicon handle wafer and buried oxide layer.



Step Four:

Deposit low stress metal. Lithographically pattern and DRIE etch to release silicon microstructures.

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